

## ABSTRACT OF THE DISCLOSURE

A reticle stage moves while holding the reticle.

A stage controller detects the acceleration of the

5 reticle stage based on the results of detection of an

laser interference system. A main control system

controls movement of the reticle stage so that the

acceleration detected by the reticle stage becomes

within a predetermined range of acceleration of the

10 reticle stage where offset will not occur in the

reticle. An image of the pattern formed on the reticle

is transferred to a wafer through a projection optical

system while synchronously moving the reticle and the

wafer.

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